

## CASE SE/2-22853/A/PCT

## CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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Date

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF

Group Art Unit: 1755

PATRICE BUJARD ET AL

Examiner: HAILEY, PATRICIA L.

APPLICATION NO: 10/517,283

FILED: DECEMBER 8, 2004

FOR: PLANE-PARALLEL STRUCTURES OF

SILICON/SILICON OXIDE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## **DECLARATION UNDER RULE 132**

Hilmar Weinert, the undersigned, states:

That I received a Degree in Chemical Engineering from the technical University of Munich;

That I have approximately 30 years research and development experience.

That I invented the subject matter disclosed but not claimed in U.S. Pub. Pat. Appl. No. 2005/0161678 related to plane parallel structures of  $SiO_y$  wherein  $1 \le y \le 1.8$ ,  $SiO_2$  flakes having "a high plane-parallelism" and various uses thereof, in particular the material of paragraph 62

and 147-1692 of the US Published application relied on by the Examiner for rejections of claims 1-6, 9-11 and 13-18.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under 18 U.S.C. § 1001, and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Hilmar Weinert